	Type	Hits	Search Text	DBs	Time Stamp
1	BRS	328	cell adj dielectric adj layer	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 16:11
2	BRS	6	cell adj dielectric adj layer same oxidizing	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 16:11
3	BRS	13	("5382533" \| "5416045" \| "5479955" \| "5569936" \| "5595923" \| "5595944" \| "5606179" \| "5624865" \| "5646075" \| "5646424" \| "5840600" \| "6291364" \| "6423649").PN.	USPAT	2004/09/04 16:12
4	BRS	12	("5382533" \| "5416045" \| "5479955" \| "5569936" \| "5595923" \| "5595944" \| "5606179" \| "5624865" \| "5646075" \| "5646424" \| "5840600" \| "6291364").PN.	USPAT	2004/09/04 16:12
5	BRS	11	("5382533" \| "5416045" \| "5479955" \| "5569936" \| "5595923" \| "5595944" \| "5606179" \| "5624865" \| "5646075" \| "5646424" \| "5840600").PN.	USPAT	2004/09/04 16:12
6	BRS	69	catalytic adj matrix	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 17:25
7	BRS	11	catalytic adj matrix same (metal or metals)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 16:28
8	BRS	18	catalytic adj matrix same (lead Pb platinum Pt iridium Ir palladium Pd rhodium Rh nickel Ni silver Ag)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 16:34
9	BRS	315	(oxidiz$5) same "N.sub.2 O" same atmosphere	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 16:48
10	BRS	98	((oxidiz$5) same "N.sub.2 O" same atmosphere) and (silicon adj substrate) and oxide and nitride	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 16:49
11	BRS	74	((oxidiz$5) same "N.sub.2 O" same atmosphere) and (silicon adj substrate) and oxide and nitride and pressure	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 16:49

	Type	Hits	Search Text	DBs	Time Stamp
12	BRS	3	((oxidiz$5) same "N.sub.2 O" same atmosphere) and (silicon adj substrate) and oxide and nitride and pressure and (catalytic adj matrix)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 16:39
13	BRS	64	((oxidiz$5) same "N.sub.2 O" same atmosphere) and (silicon adj substrate) and oxide and nitride and pressure and dielectric	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 16:41
14	BRS	154	(oxidiz$5) with "N.sub.2 O" with atmosphere	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 16:49
15	BRS	39	((oxidiz$5) with "N.sub.2 O" with atmosphere) and (silicon adj substrate) and oxide and nitride	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 17:52
16	BRS	27	((oxidiz$5) with "N.sub.2 O" with atmosphere) and (silicon adj substrate) and oxide and nitride and pressure	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 16:50
17	BRS	71	((oxidiz$5) same "N.sub.2 O" same atmosphere) and (silicon adj substrate) and oxide and nitride and pressure and temperature	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 16:49
18	BRS	27	((oxidiz$5) with "N.sub.2 O" with atmosphere) and (silicon adj substrate) and oxide and nitride and pressure and temperature	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 17:02
19	BRS	22	((oxidiz$5) with "N.sub.2 O" with atmosphere) and pressure with oxidiz$5 and temperature with oxidiz$5	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 17:03
20	BRS	6	((oxidiz$5) with "N.sub.2 O" with atmosphere) and pressure with oxidiz$5 and temperature with oxidiz$5 and (silicon adj substrate) and ((nitride oxide) adj layer)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 17:04
21	BRS	3	catalytic adj matrix same "N.sub.2 O"	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 17:26
22	BRS	5	catalytic adj matrix same oxidiz$5	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 17:26

	Type	Hits	Search Text	DBs	Time Stamp
23	BRS	30	("5382533" "5416045" "5479955" "5569936" "5595923" "5595944" "5606179" "5624865" "5646075" "5646424" "5840600" "6291364" "6423649" "6596651").pn.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 17:30
24	BRS	2	((oxidiz$5) with "N.sub.2 O" with atmosphere) and (silicon adj substrate) and (tantalum adj oxide adj (layer or film))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 17:53
25	BRS	76	(silicon adj substrate) and (oxidiz$5 with (tantalum adj oxide adj (layer or film)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 17:57
26	BRS	0	(silicon adj substrate) and (oxidiz$5 with (strontium adj bismuth adj titanate adj oxide adj (layer or film)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 18:01
27	BRS	5	(silicon adj substrate) and ((strontium adj bismuth adj titanate adj oxide adj (layer or film)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 17:59
28	BRS	5	(silicon adj substrate) and ((strontium adj bismuth adj titanate adj oxide))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 17:59
29	BRS	5	((strontium adj bismuth adj titanate adj oxide))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 17:59
30	BRS	0	(silicon adj substrate) and (oxidiz$5 with (barium adj strontium adj titanium adj oxide adj (layer or film)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 18:01
31	BRS	7	(silicon adj substrate) and ((barium adj strontium adj titanium adj oxide adj (layer or film)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 18:02
32	BRS	339	(silicon adj substrate) and (((barium adj strontium adj titanium adj oxide) or BST) adj (layer or film))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 18:04
33	BRS	3	(silicon adj substrate) and (((barium adj strontium adj titanium adj oxide) or BST) adj (layer or film)) and ((oxidiz$5) with "N.sub.2 O" with atmosphere)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 18:04
34	BRS	222	438/769.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 18:13

	Type	Hits	Search Text	DBs	Time Stamp
35	BRS	858	438/770.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 18:13
36	BRS	45	438/903.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/09/04 18:13

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Inventor Name Search Result

Your Search was:

Last Name = GEALY
First Name = F.

Application#	Patent#	Status	Date Filed	Title	Inventor Name 49
10863048	Not Issued	020	06/07/2004	ATOMIC LAYER DEPOSITION METHODS	GEALY, F. DANIEL
10822062	Not Issued	030	04/08/2004	DEVICES COMPRISING ALUMINUM OXIDE AND METAL OXIDE DIELECTRIC MATERIALS, CAPACITOR CONSTRUCTIONS, AND METHODS OF FORMING CAPACITOR CONSTRUCTIONS	GEALY, F. DANIEL
10822016	Not Issued	020	04/08/2004	METHODS OF FORMING MATERIAL OVER SUBSTRATES	GEALY, F. DANIEL
10813543	Not Issued	030	03/30/2004	METHOD FOR REDUCING PHYSISORPTION DURING ATOMIC LAYER DEPOSITION	GEALY, F. DAN
10792762	Not Issued	041	03/05/2004	MULTILAYER ELECTRODE FOR A FERROELECTRIC CAPACITOR	GEALY, F. DANIEL
10773780	Not Issued	041	02/09/2004	COMPRISING AGGLOMERATES OF ONE OR MORE NOBLE METALS	GEALY, F. DANIEL
10704284	Not Issued	030	11/06/2003	CAPACITOR CONSTRUCTIONS	GEALY, F. DANIEL
10636035	Not Issued	041	08/06/2003	METHODS OF FORMING CAPACITORS	GEALY, F. DANIEL
10624817	Not Issued	030	07/22/2003	METHOD FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	GEALY, F. DANIEL
10613191	6785120	150	07/03/2003	METHODS OF FORMING HAFNIUM-CONTAINING MATERIALS, METHODS OF FORMING HAFNIUM OXIDE,	GEALY, F. DANIEL

				AND CAPACITOR CONSTRUCTIONS COMPRISING HAFNIUM OXIDE	
10453394	6784083	150	06/03/2003	METHOD AND APPARATUS FOR REDUCING PHYSISORPTION DURING ATOMIC LAYER DEPOSITION	GEALY, F. DAN
10449039	Not Issued	030	05/30/2003	METHODS OF FORMING CAPACITORS AND ELECTRONIC DEVICES	GEALY, F. DANIEL
10435103	Not Issued	094	05/09/2003	METHODS OF FORMING CAPACITOR CONSTRUCTIONS, AND METHODS OF FORMING CONSTRUCTIONS COMPRISING DIELECTRIC MATERIALS	GEALY, F. DANIEL
10346643	6781864	150	01/16/2003	SYSTEM AND METHOD FOR INHIBITING IMPRINTING OF CAPACITOR STRUCTURES OF A MEMORY	GEALY, F. DANIEL
10299752	Not Issued	061	11/19/2002	METHOD OF FORMING A CAPACITOR	GEALY, F. DANIEL
10299728	Not Issued	041	11/19/2002	METHOD OF FORMING A DEVICE	GEALY, F. DANIEL
10299145	Not Issued	071	11/19/2002	METHOD OF FORMING A CAPACITOR	GEALY, F. DANIEL
10233590	6746916	150	09/04/2002	METHOD FOR FORMING A MULTILAYER ELECTRODE FOR A FERROELECTRIC CAPACITOR	GEALY, F. DANIEL
10231789	6773984	150	08/29/2002	METHODS OF DEPOSITING NOBLE, METALS AND METHODS OF FORMING CAPACITOR CONSTRUCTIONS	GEALY, F. DANIEL
10223805	Not Issued	041	08/19/2002	CAPACITOR CONSTRUCTIONS WITH A BARRIER LAYER TO THRESHOLD VOLTAGE SHIFT INDUCING MATERIAL	GEALY, F. DANIEL
10222304	Not Issued	092	08/15/2002	DEPOSITION METHODS	GEALY, F. DANIEL
10222282	6753271	150	08/15/2002	ATOMIC LAYER DEPOSITION METHODS	GEALY, F. DANIEL
10212892	6596651	150	08/05/2002	METHOD FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR	GEALY, F. DANIEL

				DEVICE	
10197042	Not Issued	061	07/17/2002	NOVEL DIELECTRIC STACK AND METHOD OF MAKING SAME	GEALY, F. DANIEL
10172253	Not Issued	071	06/14/2002	METHOD OF FORMING A CAPACITOR	GEALY, F. DANIEL
10159695	6689657	150	05/30/2002	METHOD OF FORMING A CAPACITOR	GEALY, F. DANIEL
10039215	Not Issued	061	01/03/2002	TOP ELECTRODE IN A STRONGLY OXIDIZING ENVIRONMENT	GEALY, F. DANIEL
10022036	6522570	150	12/13/2001	SYSTEM AND METHOD FOR INHIBITING IMPRINTING OF CAPACITOR STRUCTURES OF A MEMORY	GEALY, F. DANIEL
10015811	Not Issued	094	11/02/2001	ELECTRICAL CONTACT FOR HIGH DIELECTRIC CONSTANT CAPACITORS AND METHOD FOR FABRICATING THE SAME	GEALY, F. DANIEL
09930960	6777739	150	08/17/2001	MULTILAYER ELECTRODE FOR A FERROELECTRIC CAPACITOR	GEALY, F. DANIEL
09930958	6744093	150	08/17/2001	MULTILAYER ELECTRODE FOR A FERROELECTRIC CAPACITOR	GEALY, F. DANIEL
09910168	6423649	150	07/20/2001	METHOD AND APPARATUS FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	GEALY, F. DANIEL
09879335	Not Issued	089	06/11/2001	CAPACITOR FORMING METHODS WITH BARRIER LAYERS TO THRESHOLD VOLTAGE SHIFT INDUCING MATERIAL	GEALY, F. DANIEL
09846520	6400552	150	04/30/2001	CAPACITOR WITH CONDUCTIVELY DOPED SI-GE ALLOY ELECTRODE	GEALY, F. DANIEL
09770699	Not Issued	041	01/26/2001	CAPACITOR HAVING AN ELECTRODE FORMED FROM A TRANSITION METAL OR A CONDUCTIVE METAL-OXIDE, AND METHOD OF FORMING SAME	GEALY, F. DANIEL
09684069	6627508	150	10/06/2000	METHOD OF FORMING CAPACITORS CONTAINING TANTALUM	GEALY, F. DANIEL
09652863	6682969	150	08/31/2000	TOP ELECTRODE IN A	GEALY, F.

				STRONGLY OXIDIZING ENVIRONMENT	DANIEL
09630850	6773981	150	08/02/2000	METHODS OF FORMING CAPACITORS	GEALY, F. DANIEL
09516422	6610211	150	03/01/2000	METHOD OF PROCESSING INTERNAL SURFACES OF A CHEMICAL VAPOR DEPOSITION REACTOR	GEALY, F. DANIEL
09386941	6291364	150	08/31/1999	METHOD AND APPARATUS FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	GEALY, F. DANIEL
09310408	6297527	150	05/12/1999	MULTILAYER ELECTRODE FOR FERROELECTRIC AND HIGH DIELECTRIC CONSTANT CAPACITORS	GEALY , F. DANIEL
09286807	6696718	150	04/06/1999	CAPACITOR HAVING AN ELECTRODE FORMED FROM A TRANSITION METAL OR A CONDUCTIVE METAL-OXIDE, AND METHOD OF FORMING SAME	GEALY , F. DANIEL
09268176	6348709	150	03/15/1999	ELECTRICAL CONTACT FOR HIGH DIELECTRIC CONSTANT CAPACITORS AND METHOD FOR FABRICATING THE SAME	GEALY , F. DANIEL
09229518	6282080	150	01/13/1999	SEMICONDUCTOR CIRCUIT COMPONENTS AND CAPACITORS	GEALY , F. DANIEL
09098035	6146959	150	06/15/1998	METHOD OF FORMING CAPACITORS CONTAINING TANTALUM	GEALY , F. DANIEL
09083258	6082375	150	05/21/1998	METHOD OF PROCESSING INTERNAL SURFACES OF A CHEMICAL VAPOR DEPOSITION REACTOR	GEALY , F. DANIEL
09033063	6191443	150	02/28/1998	CAPACITORS, METHODS OF FORMING CAPACITORS, AND DRAM MEMORY CELLS	GEALY, F. DANIEL
08916771	5910880	150	08/20/1997	SEMICONDUCTOR CIRCUIT COMPONENTS AND CAPACITORS	GEALY , F. DANIEL
08511275	Not Issued	161	08/03/1995	MIXED GAS RAPID THERMAL PROCESS OXIDATION ANNEALS FOR FERROELECTRIC DIELECTRICS	GEALY , F. DANIEL

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GEALY	F.

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Inventor Name Search Result

Your Search was:

Last Name = CHAPEK
First Name = DAVE

Application#	Patent#	Status	Date Filed	Title	Inventor Name 5
10624817	Not Issued	030	07/22/2003	METHOD FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	CHAPEK, DAVE
10212892	6596651	150	08/05/2002	METHOD FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	CHAPEK, DAVE
09910168	6423649	150	07/20/2001	METHOD AND APPARATUS FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	CHAPEK, DAVE
09798445	Not Issued	094	03/02/2001	METHOD AND APPARATUS FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	CHAPEK, DAVE
09386941	6291364	150	08/31/1999	METHOD AND APPARATUS FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	CHAPEK, DAVE

Inventor Search Completed: No Records to Display.

Search Another: Inventor

Last Name	First Name
CHAPEK	DAVE

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Inventor Name Search Result

Your Search was:

Last Name = DEBOER
First Name = SCOTT

Application#	Patent#	Status	Date Filed	Title	Inventor Name 51
10881630	Not Issued	020	06/30/2004	CONDUCTOR LAYER NITRIDATION	DEBOER, SCOTT
10789890	Not Issued	020	02/27/2004	SELECTIVE SPACER TECHNOLOGY TO PREVENT METAL OXIDE FORMATION DURING POLYCIDE REOXIDATION	DEBOER, SCOTT JEFFREY
10786348	Not Issued	041	02/24/2004	DOUBLE SIDED CONTAINER PROCESS USED DURING THE MANUFACTURE OF A SEMICONDUCTOR DEVICE	DEBOER, SCOTT J.
10771042	Not Issued	030	02/03/2004	CAPACITOR STRUCTURES WITH RECESSED HEMISPHERICAL GRAIN SILICON	DEBOER, SCOTT J.
10769573	Not Issued	030	01/30/2004	GATED SEMICONDUCTOR ASSEMBLIES AND METHODS OF FORMING GATED SEMICONDUCTOR ASSEMBLIES	DEBOER, SCOTT JEFFREY
10734419	Not Issued	030	12/11/2003	SEMICONDUCTOR WAFER ASSEMBLIES COMPRISING PHOTORESIST OVER SILICON NITRIDE MATERIALS	DEBOER, SCOTT JEFFREY
10714688	Not Issued	041	11/17/2003	METHOD AND STRUCTURE FOR REDUCING CONTACT ASPECT RATIOS	DEBOER, SCOTT J.
10640309	Not Issued	019	01/01/0001	FABRICATION OF DRAM AND OTHER SEMICONDUCTOR DEVICES WITH AN INSULATING FILM USING A WET RAPID THERMAL OXIDATION PROCESS	DEBOER, SCOTT J.
10624817	Not Issued	030	07/22/2003	METHOD FOR STABILIZING	DEBOER,

				HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	SCOTT
10060894	6593616	150	01/29/2002	BURIED BIT LINE MEMORY CIRCUITRY	DEBOER, SCOTT JEFFREY
09997660	6670238	150	11/28/2001	METHOD AND STRUCTURE FOR REDUCING CONTACT ASPECT RATIOS	DEBOER, SCOTT J.
09996337	Not Issued	094	11/28/2001	RAISED-LINES OVERLAYS SEMICONDUCTOR TARGETS AND METHOD OF MAKING THE SAME	DEBOER, SCOTT J.
09995372	6693345	150	11/26/2001	SEMICONDUCTOR WAFER ASSEMBLIES COMPRISING PHOTORESIST OVER SILICON NITRIDE MATERIALS	DEBOER, SCOTT JEFFREY
09982294	6566222	150	10/16/2001	METHODS OF FORMING RECESSED HEMISPHERICAL GRAIN SILICON CAPACITOR STRUCTURES	DEBOER, SCOTT J.
09951153	Not Issued	092	09/12/2001	STRUCTURES COMPRISING A LAYER FREE OF NITROGEN BETWEEN SILICON NITRIDE AND PHOTORESIST	DEBOER, SCOTT JEFFREY
09943180	Not Issued	061	08/29/2001	METHODS OF FORMING CAPACITORS	DEBOER, SCOTT J.
09930961	6635547	150	08/17/2001	DRAM CAPACITOR FORMULATION USING A DOUBLE-SIDED ELECTRODE	DEBOER, SCOTT J.
09912649	6469336	150	07/23/2001	STRUCTURE FOR REDUCING CONTACT ASPECT RATIOS	DEBOER, SCOTT J.
09912558	Not Issued	061	07/26/2001	FABRICATION OF DRAM AND OTHER SEMICONDUCTOR DEVICES WITH AN INSULATING FILM USING A WET RAPID THERMAL OXIDATION PROCESS	DEBOER, SCOTT J.
09912153	6455365	150	07/23/2001	STRUCTURAL INTEGRITY ENHANCEMENT OF DIELECTRIC FILMS	DEBOER, SCOTT J.
09910168	6423649	150	07/20/2001	METHOD AND APPARATUS FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	DEBOER, SCOTT
09892594	6399459	150	06/27/2001	DOUBLE LAYER ELECTRODE AND BARRIER SYSTEM ON	DEBOER, SCOTT

				HEMISPHERICAL GRAIN SILICON FOR USE WITH HIGH DIELECTRIC CONSTANT MATERIALS AND METHODS FOR FABRICATING THE SAME	
09864552	6531728	150	05/23/2001	OXIDE ETCHING METHOD AND STRUCTURES RESULTING FROM SAME	DEBOER, SCOTT J.
09859204	Not Issued	093	05/15/2001	ETCHING PROCESSES	DEBOER, SCOTT JEFFREY
09855217	6696336	150	05/14/2001	DOUBLE SIDED CONTAINER PROCESS USED DURING THE MANUFACTURE OF A SEMICONDUCTOR DEVICE	DEBOER, SCOTT J.
09846520	6400552	150	04/30/2001	CAPACITOR WITH CONDUCTIVELY DOPED SI-GE ALLOY ELECTRODE	DEBOER, SCOTT JEFFREY
09827973	6368962	150	04/05/2001	SEMICONDUCTOR PROCESSING METHOD OF FORMING A CONDUCTIVE LINE, AND BURIED BIT LINE MEMORY CIRCUITRY	DEBOER, SCOTT JEFFREY
09823133	6404005	150	03/29/2001	METHODS OF FORMING CAPACITORS AND RELATED INTEGRATED CIRCUITRY	DEBOER, SCOTT J.
09765122	Not Issued	161	01/17/2001	METHOD OF FORMING HIGH ASPECT RATIO STRUCTURES FOR SEMICONDUCTOR DEVICES	DEBOER, SCOTT
09739270	6613654	150	12/19/2000	FABRICATION OF SEMICONDUCTOR DEVICES WITH TRANSITION METAL BORIDE FILMS AS DIFFUSION BARRIERS	DEBOER, SCOTT J.
09713845	6426306	150	11/15/2000	BARRIER LAYER FABRICATION METHODS	DEBOER, SCOTT J.
09684069	6627508	150	10/06/2000	METHOD OF FORMING CAPACITORS CONTAINING TANTALUM	DEBOER, SCOTT JEFFREY
09652910	6632719	150	08/31/2000	CAPACITOR STRUCTURES WITH RECESSED HEMISPHERICAL GRAIN SILICON	DEBOER, SCOTT J.
09651790	Not Issued	092	08/30/2000	RESIDUE FREE OVERLAY TARGET	DEBOER, SCOTT J.

09651377	6486020	150	08/29/2000	HIGH PRESSURE REOXIDATION/ANNEAL OF HIGH DIELECTRIC CONSTANT MATERIALS	DEBOER, SCOTT JEFFREY
09630850	6773981	150	08/02/2000	METHODS OF FORMING CAPACITORS	DEBOER, SCOTT JEFFREY
09619468	6429151	150	07/19/2000	SEMICONDUCTOR WAFER ASSEMBLIES COMPRISING SILICON NITRIDE, METHODS OF FORMING SILICON NITRIDE, AND METHODS OF REDUCING STRESS ON SEMICONDUCTIVE WAFERS	DEBOER, SCOTT J.
09615549	Not Issued	092	07/13/2000	CAPACITOR ELECTRODE HAVING AN INTERFACE LAYER OF DIFFERENT CHEMICAL COMPOSITION FORMED ON A BULK LAYER	DEBOER, SCOTT J.
09604850	6670288	150	06/27/2000	METHODS OF FORMING A LAYER OF SILICON NITRIDE IN A SEMICONDUCTOR FABRICATION PROCESS	DEBOER, SCOTT JEFFREY
09604849	6326321	150	06/27/2000	METHODS OF FORMING A LAYER OF SILICON NITRIDE IN SEMICONDUCTOR FABRICATION PROCESSES	DEBOER, SCOTT JEFFREY
09603147	Not Issued	061	06/23/2000	CAPACITOR CONSTRUCTIONS, DRAM CONSTRUCTIONS, AND SEMICONDUCTIVE MATERIAL ASSEMBLIES	DEBOER, SCOTT JEFFREY
09602834	Not Issued	041	06/23/2000	METHODS OF FORMING DRAMS	DEBOER, SCOTT JEFFREY
09602832	6391710	150	06/23/2000	METHODS OF FORMING CAPACITORS	DEBOER, SCOTT JEFFREY
09602616	Not Issued	071	06/23/2000	ETCHING PROCESSES	DEBOER, SCOTT JEFFREY
09563909	6316800	150	05/04/2000	BORIDE ELECTRODES AND BARRIERS FOR CELL DIELECTRICS	DEBOER, SCOTT J.
09516422	6610211	150	03/01/2000	METHOD OF PROCESSING INTERNAL SURFACES OF A CHEMICAL VAPOR DEPOSITION REACTOR	DEBOER, SCOTT JEFFREY

09506177	6528436	150	02/17/2000	METHOD OF FORMING SILICON NITRIDE LAYER DIRECTLY ON HSG POLYSILICON	DEBOER, SCOTT JEFFREY
09488947	6440860	150	01/18/2000	SEMICONDUCTOR PROCESSING METHODS OF TRANSFERRING PATTERNS FROM PATTERNED PHOTORESISTS TO MATERIALS, AND STRUCTURES COMPRISING SILICON NITRIDE	DEBOER, SCOTT JEFFREY
09386941	6291364	150	08/31/1999	METHOD AND APPARATUS FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	DEBOER, SCOTT
09042791	6111285	150	03/17/1998	BORIDE ELECTRODES AND BARRIERS FOR CELL DIELECTRICS	DEBOER, SCOTT J.
09033063	6191443	150	02/28/1998	CAPACITORS, METHODS OF FORMING CAPACITORS, AND DRAM MEMORY CELLS	DEBOER, SCOTT JEFFREY

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Last Name = DEBOER
First Name = SCOTT

Application#	Patent#	Status	Date Filed	Title	Inventor Name 51
10418664	Not Issued	071	04/17/2003	METHOD OF FORMING A CAPACITOR DIELECTRIC LAYER	DEBOER, SCOTT J.
10418532	Not Issued	061	04/17/2003	CAPACITORS	DEBOER, SCOTT J.
10417119	Not Issued	071	04/17/2003	FABRICATION OF SEMICONDUCTOR DEVICES WITH TRANSITION METAL BORIDE FILMS AS DIFFUSION BARRIERS	DEBOER, SCOTT J.
10235516	6677636	150	09/04/2002	STRUCTURE FOR REDUCING CONTACT ASPECT RATIOS	DEBOER, SCOTT J.
10235452	6720609	150	09/04/2002	STRUCTURE FOR REDUCING CONTACT ASPECT RATIOS	DEBOER, SCOTT J.
10232206	Not Issued	071	08/29/2002	CAPACITOR HAVING TANTALUM OXYNITRIDE FILM AND METHOD FOR MAKING SAME	DEBOER, SCOTT JEFFREY
10232205	Not Issued	041	08/29/2002	CAPACITOR HAVING TANTALUM OXYNITRIDE FILM AND METHOD FOR MAKING SAME	DEBOER, SCOTT JEFFREY
10231758	Not Issued	095	08/29/2002	CONDUCTOR LAYER NITRIDATION	DEBOER, SCOTT
10226356	6607953	150	08/21/2002	STRUCTURAL INTEGRITY ENHANCEMENT OF DIELECTRIC FILMS	DEBOER, SCOTT J.
10213812	Not Issued	041	08/07/2002	METHODS FOR FORMING A HIGH DIELECTRIC FILM	DEBOER, SCOTT J.
10212892	6596651	150	08/05/2002	METHOD FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	DEBOER, SCOTT

10161136	Not Issued	094	05/30/2002	SEMICONDUCTOR PROCESSING METHODS OF TRANSFERRING PATTERNS FROM PATTERNED PHOTORESISTS TO MATERIALS, AND STRUCTURES COMPRISING SILICON NITRIDE	DEBOER, SCOTT JEFFREY
10161134	Not Issued	061	05/30/2002	SEMICONDUCTOR PROCESSING METHODS OF TRANSFERRING PATTERNS FROM PATTERNED PHOTORESISTS TO MATERIALS, AND STRUCTURES COMPRISING SILICON NITRIDE	DEBOER, SCOTT JEFFREY
10160705	Not Issued	071	05/30/2002	SEMICONDUCTOR PROCESSING METHODS OF TRANSFERRING PATTERNS FROM PATTERNED PHOTORESISTS TO MATERIALS, AND STRUCTURES COMPRISING SILICON NITRIDE	DEBOER, SCOTT JEFFREY
10160698	Not Issued	092	05/30/2002	SEMICONDUCTOR PROCESSING METHODS OF TRANSFERRING PATTERNS FROM PATTERNED PHOTORESISTS TO MATERIALS, AND STRUCTURES COMPRISING SILICON NITRIDE	DEBOER, SCOTT JEFFREY
10159892	6673689	150	05/30/2002	DOUBLE LAYER ELECTRODE AND BARRIER SYSTEM ON HEMISPHERICAL GRAIN SILICON FOR USE WITH HIGH DIELECTRIC CONSTANT MATERIALS AND METHODS FOR FABRICATING THE SAME	DEBOER, SCOTT
10133390	Not Issued	061	04/29/2002	FABRICATION OF DRAM AND OTHER SEMICONDUCTOR DEVICES WITH AN INSULATING FILM USING A WET RAPID THERMAL OXIDATION PROCESS	DEBOER, SCOTT J.
10116385	6548405	150	04/02/2002	BATCH PROCESSING FOR SEMICONDUCTOR WAFERS TO FORM ALUMINUM NITRIDE	DEBOER, SCOTT J.

				AND TITANIUM ALUMINUM NITRIDE	
09941759	6518121	150	08/30/2001	BORIDE ELECTRODES AND BARRIERS FOR CELL DIELECTRICS	DEBOER, SCOTT J.
09836123	6365519	150	04/16/2001	BATCH PROCESSING FOR SEMICONDUCTOR WAFERS TO FORM ALUMINUM NITRIDE AND TITANIUM ALUMINUM NITRIDE	DEBOER, SCOTT J.
09798445	Not Issued	094	03/02/2001	METHOD AND APPARATUS FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	DEBOER, SCOTT
09765122	Not Issued	161	01/17/2001	METHOD OF FORMING HIGH ASPECT RATIO STRUCTURES FOR SEMICONDUCTOR DEVICES	DEBOER, SCOTT
09724749	6417559	150	11/27/2000	SEMICONDUCTOR WAFER ASSEMBLIES COMPRISING PHOTORESIST OVER SILICON NITRIDE MATERIALS	DEBOER, SCOTT JEFFREY
09457093	6323139	150	12/07/1999	SEMICONDUCTOR PROCESSING METHODS OF FORMING PHOTORESIST OVER SILICON NITRIDE MATERIALS	DEBOER , SCOTT JEFFREY
09296835	Not Issued	041	04/22/1999	FABRICATION OF DRAM AND OTHER SEMICONDUCTOR DEVICES WITH AN INSULATING FILM USING A WET RAPID THERMAL OXIDATION PROCESS	DEBOER , SCOTT J.
09293635	6204143	150	04/15/1999	METHOD OF FORMING HIGH ASPECT RATIO STRUCTURES FOR SEMINCONDUCTOR DEVICES	DEBOER , SCOTT
09240395	6614082	150	01/29/1999	FABRICATION OF SEMICONDUCTOR DEVICES WITH TRANSITION METAL BORIDE FILMS AS DIFFUSION BARRIERS	DEBOER , SCOTT J.
09229518	6282080	150	01/13/1999	SEMICONDUCTOR CIRCUIT COMPONENTS AND CAPACITORS	DEBOER , SCOTT JEFFREY
09191294	6218293	150	11/13/1998	BATCH PROCESSING FOR SEMICONDUCTOR WAFERS TO	DEBOER , SCOTT J.

				FORM ALUMINUM NITRIDE AND TITANIUM ALUMINUM NITRIDE	
09191156	6340613	150	11/12/1998	STRUCTURAL INTEGRITY ENHANCEMENT OF DIELECTRIC FILMS	DEBOER , SCOTT J.
09175051	6251802	150	10/19/1998	METHODS OF FORMING CARBON-CONTAINING LAYERS	DEBOER , SCOTT JEFFREY
09136882	6194321	150	08/19/1998	SEMICONDUCTOR PROCESSING METHODS UTILIZING BORON AND NITROGEN, AND SEMICONDUCTOR WAFERS COMPRISING BORON AND NITROGEN	DEBOER , SCOTT JEFFREY
09100530	6093956	150	06/18/1998	SEMICONDUCTOR WAFER ASSEMBLIES COMPRISING SILICON NITRIDE, METHODS OF FORMING SILICON NITRIDE, AND METHODS OF REDUCING STRESS ON SEMICONDUCTIVE WAFERS	DEBOER , SCOTT J
09057155	6300253	150	04/07/1998	SEMICONDUCTOR PROCESSING METHODS OF PATTERNING SILICON NITRIDE MATERIALS WITH PHOTORESIST	DEBOER , SCOTT J.
09057153	6316372	150	04/07/1998	METHODS OF FORMING A LAYER OF SILICON NITRIDE IN A SEMICONDUCTOR FABRICATION PROCESS	DEBOER , SCOTT JEFFREY
09057152	5985771	150	04/07/1998	SEMICONDUCTOR WAFER ASSEMBLIES COMPRISING SILICON NITRIDE METHODS OF FORMING SILICON NITRIDE AND METHODS OF REDUCING STRESS ON SEMICONDUCTIVE WAFERS	DEBOER , SCOTT J.
09057148	6635530	150	04/07/1998	METHODS OF FORMING GATED SEMICONDUCTOR ASSEMBLIES	DEBOER , SCOTT JEFFREY
09033064	6162744	150	02/28/1998	METHOD OF FORMING HIGH-K OXYGEN-CONTAINING DIELECTRIC LAYERS INCLUDING MANUFACTURE OF CAPACITORS AND DRAM CELLS	DEBOER , SCOTT JEFFREY

09031526	6458645	150	02/26/1998	CAPACITOR HAVING TANTALUM OXYNITRIDE FILM AND METHOD FOR MAKING SAME	DEBOER , SCOTT JEFFREY
09006126	5960294	150	01/13/1998	METHOD OF FABRICATING A SEMICONDUCTOR DEVICE UTILIZING POLYSILICON GRAINS	DEBOER , SCOTT J.
09004932	6180481	150	01/09/1998	BARRIER LAYER FABRICATION METHODS	DEBOER , SCOTT J.
08916771	5910880	150	08/20/1997	SEMICONDUCTOR CIRCUIT COMPONENTS AND CAPACITORS	DEBOER , SCOTT JEFFREY
08915917	6794703	150	08/21/1997	HIGH PRESSURE REOXIDATION/ANNEAL OF HIGH DIELECTRIC CONSTANT MATERIALS	DEBOER , SCOTT JEFFREY
08902809	Not Issued	041	07/30/1997	SELECTIVE SPACER TO PREVENT METAL OXIDE FORMATION DURING POLYCIDE REOXIDATION	DEBOER , SCOTT JEFFREY
08876057	6046093	150	06/13/1997	METHOD OF FORMING CAPACITORS AND RELATED INTEGRATED CIRCUITRY	DEBOER , SCOTT J.
08803174	6015997	150	02/19/1997	SEMICONDUCTOR STRUCTURE HAVING A DOPED CONDUCTIVE LAYER	DEBOER , SCOTT
08802861	5926730	150	02/19/1997	CONDUCTOR LAYER NITRIDATION	DEBOER , SCOTT
08797900	6090723	150	02/10/1997	CONDITIONING OF DIELECTRIC MATERIALS	DEBOER , SCOTT J.
08734357	Not Issued	161	10/21/1996	THIN NITRIDE LAYER DEVICES AND METHOD FOR THEIR FORMATION	DEBOER , SCOTT J.
08720375	6251720	150	09/27/1996	HIGH PRESSURE REOXIDATION/ANNEAL OF HIGH DIELECTRIC CONSTANT MATERIALS	DEBOER , SCOTT J.
08678729	5930106	150	07/11/1996	DRAM CAPACITORS MADE FROM SILICON-GERMANIUM AND ELECTRODE-LIMITED CONDUCTION DIELECTRIC FILMS	DEBOER , SCOTT J.

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Application#	Patent#	Status	Date Filed	Title	Inventor Name 25
09454536	6337274	150	12/06/1999	BURIED BIT LINE MEMORY CIRCUITRY, METHOD OF FORMING BURIED BIT LINE MEMORY CIRCUITRY, AND SEMICONDUCTOR PROCESSING METHOD OF FORMING A CONDUCTIVE LINE	DEBOER , SCOTT JEFFREY
09438310	6756634	150	11/10/1999	GATED SEMICONDUCTOR ASSEMBLIES	DEBOER , SCOTT JEFFREY
09429220	6677661	150	10/28/1999	SEMICONDUCTIVE WAFER ASSEMBLIES	DEBOER , SCOTT JEFFREY
09415213	6451661	150	10/12/1999	DRAM CAPACITOR FORMULATION USING A DOUBLE-SIDED ELECTRODE	DEBOER , SCOTT J.
09393542	6461985	150	09/10/1999	SEMICONDUCTOR WAFER ASSEMBLIES COMPRISING SILICON NITRIDE, METHODS OF FORMING SILICON NITRIDE, AND METHODS OF REDUCING STRESS ON SEMICONDUCTIVE WAFERS	DEBOER , SCOTT J.
09393078	6239459	150	09/07/1999	CAPACITORS, METHODS OF FORMING CAPACITORS, AND INTEGRATED CIRCUITRY	DEBOER , SCOTT JEFFERY
09388685	6258729	150	09/02/1999	OXIDE ETCHING METHOD AND STRUCTURES RESULTING FROM SAME	DEBOER , SCOTT J.
09386833	6281543	150	08/31/1999	DOUBLE LAYER ELECTRODE AND BARRIER SYSTEM ON HEMISPHERICAL GRAIN SILICON FOR USE WITH HIGH	DEBOER , SCOTT

				DIELECTRIC CONSTANT MATERIALS AND METHODS FOR FABRICATING THE SAME	
09385787	6326277	150	08/30/1999	METHODS OF FORMING RECESSED HEMISPHERICAL GRAIN SILICON CAPACITOR STRUCTURES	DEBOER, SCOTT J.
09385786	6693320	150	08/30/1999	CAPACITOR STRUCTURES WITH RECESSED HEMISPHERICAL GRAIN SILICON	DEBOER, SCOTT J.
09382507	6325017	150	08/25/1999	APPARATUS FOR FORMING A HIGH DIELECTRIC FILM	DEBOER, SCOTT J.
09376886	6300671	150	08/18/1999	SEMICONDUCTOR WAFER ASSEMBLIES COMPRISING PHOTORESIST OVER SILICON NITRIDE MATERIALS	DEBOER, SCOTT J.
09334842	6365453	150	06/16/1999	METHOD AND STRUCTURE FOR REDUCING CONTACT ASPECT RATIOS	DEBOER, SCOTT J.
09296835	Not Issued	041	04/22/1999	FABRICATION OF DRAM AND OTHER SEMICONDUCTOR DEVICES WITH AN INSULATING FILM USING A WET RAPID THERMAL OXIDATION PROCESS	DEBOER, SCOTT J.
09156207	6222222	150	09/17/1998	METHODS OF FORMING CAPACITORS AND RELATED INTEGRATED CIRCUITRY	DEBOER, SCOTT J.
09137780	6255186	150	08/20/1998	METHODS OF FORMING INTEGRATED CIRCUITRY AND CAPACITORS HAVING A CAPACITOR ELECTRODE HAVING A BASE AND A PAIR OF WALLS PROJECTING UPWARDLY THEREFROM	DEBOER, SCOTT JEFFERY
09132099	Not Issued	161	08/10/1998	THIN NITRIDE LAYER DEVICES AND METHOD FOR THEIR FORMATION	DEBOER, SCOTT JEFFREY
09131993	6525384	150	08/11/1998	CONDUCTOR LAYER NITRIDATION	DEBOER, SCOTT
09098035	6146959	150	06/15/1998	METHOD OF FORMING CAPACITORS CONTAINING TANTALUM	DEBOER, SCOTT JEFFREY
09089445	6737696	150	06/03/1998	DRAM CAPACITOR FORMULATION USING A	DEBOER, SCOTT J.

				DOUBLE-SIDED ELECTRODE	
09083258	6082375	150	05/21/1998	METHOD OF PROCESSING INTERNAL SURFACES OF A CHEMICAL VAPOR DEPOSITION REACTOR	DEBOER , SCOTT JEFFREY
09083257	Not Issued	162	05/21/1998	CAPACITORS, METHODS OF FORMING CAPACITORS, AND INTEGRATED CIRCUITRY	DEBOER , SCOTT J.
09076333	6150208	150	05/11/1998	DRAM CAPACITORS MADE FROM SILICON-GERMANIUM AND ELECTRODE-LIMITED CONDUCTION DIELECTRIC FILMS	DEBOER , SCOTT J.
08807831	6461982	150	02/27/1997	METHODS FOR FORMING A DIELECTRIC FILM	DEBOER , SCOTT J.
08561735	5989338	150	11/22/1995	METHOD FOR DEPOSITING CELL NITRIDE WITH IMPROVED STEP COVERAGE USING MOCVD IN A WAFER DEPOSITION SYSTEM	DEBOER , SCOTT J.

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Last Name = AL-SHAREEF
First Name = HUSAM

Application#	Patent#	Status	Date Filed	Title	Inventor Name 39
10640309	Not Issued	019	01/01/0001	FABRICATION OF DRAM AND OTHER SEMICONDUCTOR DEVICES WITH AN INSULATING FILM USING A WET RAPID THERMAL OXIDATION PROCESS	AL-SHAREEF, HUSAM N.
10624817	Not Issued	030	07/22/2003	METHOD FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	AL-SHAREEF, HUSAM N.
10417119	Not Issued	071	04/17/2003	FABRICATION OF SEMICONDUCTOR DEVICES WITH TRANSITION METAL BORIDE FILMS AS DIFFUSION BARRIERS	AL-SHAREEF, HUSAM N.
10232206	Not Issued	071	08/29/2002	CAPACITOR HAVING TANTALUM OXYNITRIDE FILM AND METHOD FOR MAKING SAME	AL-SHAREEF, HUSAM N.
10232205	Not Issued	041	08/29/2002	CAPACITOR HAVING TANTALUM OXYNITRIDE FILM AND METHOD FOR MAKING SAME	AL-SHAREEF, HUSAM N.
10212892	6596651	150	08/05/2002	METHOD FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	AL-SHAREEF, HUSAM N.
10159892	6673689	150	05/30/2002	DOUBLE LAYER ELECTRODE AND BARRIER SYSTEM ON HEMISPHERICAL GRAIN SILICON FOR USE WITH HIGH DIELECTRIC CONSTANT MATERIALS AND METHODS FOR	AL-SHAREEF, HUSAM N.

				FABRICATING THE SAME	
10133390	Not Issued	061	04/29/2002	FABRICATION OF DRAM AND OTHER SEMICONDUCTOR DEVICES WITH AN INSULATING FILM USING A WET RAPID THERMAL OXIDATION PROCESS	AL-SHAREEF, HUSAM N.
09941759	6518121	150	08/30/2001	BORIDE ELECTRODES AND BARRIERS FOR CELL DIELECTRICS	AL-SHAREEF, HUSAM N.
09930961	6635547	150	08/17/2001	DRAM CAPACITOR FORMULATION USING A DOUBLE-SIDED ELECTRODE	AL-SHAREEF, HUSAM
09912558	Not Issued	061	07/26/2001	FABRICATION OF DRAM AND OTHER SEMICONDUCTOR DEVICES WITH AN INSULATING FILM USING A WET RAPID THERMAL OXIDATION PROCESS	AL-SHAREEF, HUSAM N.
09910168	6423649	150	07/20/2001	METHOD AND APPARATUS FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	AL-SHAREEF, HUSAM N.
09892594	6399459	150	06/27/2001	DOUBLE LAYER ELECTRODE AND BARRIER SYSTEM ON HEMISPHERICAL GRAIN SILICON FOR USE WITH HIGH DIELECTRIC CONSTANT MATERIALS AND METHODS FOR FABRICATING THE SAME	AL-SHAREEF, HUSAM N.
09846520	6400552	150	04/30/2001	CAPACITOR WITH CONDUCTIVELY DOPED SI-GE ALLOY ELECTRODE	AL-SHAREEF, HUSAM N.
09798445	Not Issued	094	03/02/2001	METHOD AND APPARATUS FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	AL-SHAREEF, HUSAM N.
09739270	6613654	150	12/19/2000	FABRICATION OF SEMICONDUCTOR DEVICES WITH TRANSITION METAL BORIDE FILMS AS	AL-SHAREEF, HUSAM N.

				DIFFUSION BARRIERS	
09705700	6720607	150	11/06/2000	METHOD FOR IMPROVING THE RESISTANCE DEGRADATION OF THIN FILM CAPACITORS	AL-SHAREEF, HUSAM N.
09630850	6773981	150	08/02/2000	METHODS OF FORMING CAPACITORS	AL-SHAREEF, HUSAM N.
09563909	6316800	150	05/04/2000	BORIDE ELECTRODES AND BARRIERS FOR CELL DIELECTRICS	AL-SHAREEF, HUSAM N.
09516422	6610211	150	03/01/2000	METHOD OF PROCESSING INTERNAL SURFACES OF A CHEMICAL VAPOR DEPOSITION REACTOR	AL-SHAREEF, HUSAM N.
09415213	6451661	150	10/12/1999	DRAM CAPACITOR FORMULATION USING A DOUBLE-SIDED ELECTRODE	AL-SHAREEF , HUSAM
09393078	6239459	150	09/07/1999	CAPACITORS, METHODS OF FORMING CAPACITORS, AND INTEGRATED CIRCUITRY	AL-SHAREEF , HUSAM N.
09388063	Not Issued	061	08/30/1999	CAPACITORS HAVING A CAPACITOR DIELECTRIC LAYER COMPRISING A METAL OXIDE HAVING MULTIPLE DIFFERENT METALS BONDED WITH OXYGEN	AL-SHAREEF , HUSAM N.
09386941	6291364	150	08/31/1999	METHOD AND APPARATUS FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	AL-SHAREEF, HUSAM N.
09386833	6281543	150	08/31/1999	DOUBLE LAYER ELECTRODE AND BARRIER SYSTEM ON HEMISPHERICAL GRAIN SILICON FOR USE WITH HIGH DIELECTRIC CONSTANT MATERIALS AND METHODS FOR FABRICATING THE SAME	AL-SHAREEF , HUSAM N.
09296835	Not Issued	041	04/22/1999	FABRICATION OF DRAM AND OTHER SEMICONDUCTOR DEVICES WITH AN INSULATING FILM USING A WET RAPID	AL-SHAREEF , HUSAM N.

				THERMAL OXIDATION PROCESS	
09259259	6258655	150	03/01/1999	METHOD FOR IMPROVING THE RESISTANCE DEGRADATION OF THIN FILM CAPACITORS	AL-SHAREEF , HUSAM N.
09240395	6614082	150	01/29/1999	FABRICATION OF SEMICONDUCTOR DEVICES WITH TRANSITION METAL BORIDE FILMS AS DIFFUSION BARRIERS	AL-SHAREEF , HUSAM N.
09156545	6124164	150	09/17/1998	METHOD OF MAKING INTEGRATED CAPACITOR INCORPORATING HIGH K DIELECTRIC	AL-SHAREEF , HUSAM N.
09137780	6255186	150	08/20/1998	METHODS OF FORMING INTEGRATED CIRCUITRY AND CAPACITORS HAVING A CAPACITOR ELECTRODE HAVING A BASE AND A PAIR OF WALLS PROJECTING UPWARDLY THEREFROM	AL-SHAREEF , HUSAM N.
09089445	6737696	150	06/03/1998	DRAM CAPACITOR FORMULATION USING A DOUBLE-SIDED ELECTRODE	AL-SHAREEF , HUSAM
09083258	6082375	150	05/21/1998	METHOD OF PROCESSING INTERNAL SURFACES OF A CHEMICAL VAPOR DEPOSITION REACTOR	AL-SHAREEF , HUSAM N.
09083257	Not Issued	162	05/21/1998	CAPACITORS, METHODS OF FORMING CAPACITORS, AND INTEGRATED CIRCUITRY	AL-SHAREEF , HUSAM N.
09042791	6111285	150	03/17/1998	BORIDE ELECTRODES AND BARRIERS FOR CELL DIELECTRICS	AL-SHAREEF , HUSAM N.
09033064	6162744	150	02/28/1998	METHOD OF FORMING HIGH-K OXYGEN-CONTAINING DIELECTRIC LAYERS INCLUDING MANUFACTURE OF CAPACITORS AND DRAM CELLS	AL-SHAREEF , HUSAM N.
09033063	6191443	150	02/28/1998	CAPACITORS, METHODS OF FORMING CAPACITORS,	AL-SHAREEF, HUSAM N.

				AND DRAM MEMORY CELLS	
09031526	6458645	150	02/26/1998	CAPACITOR HAVING TANTALUM OXYNITRIDE FILM AND METHOD FOR MAKING SAME	AL-SHAREEF , HUSAM N.
08807334	6096127	150	02/28/1997	TUNEABLE DIELECTRIC FILMS HAVING LOW ELECTRICAL LOSSES	AL-SHAREEF , HUSAM NIMAN
08365781	5555486	150	12/29/1994	HYBRID METAL/METAL OXIDE ELECTRODES FOR FERROELECTRIC CAPACITORS	AL-SHAREEF , HUSAM N.

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Last Name = THAKUR
First Name = RANDHIR

Application#	Patent#	Status	Date Filed	Title	Inventor Name 51
10866471	Not Issued	019	06/10/2004	LOW TEMPERATURE EPITAXIAL GROWTH OF SILICON-CONTAINING FILMS USING UV RADIATION	THAKUR, RANDHIR
10851514	Not Issued	030	05/21/2004	STABILIZATION OF HIGH-K DIELECTRIC MATERIALS	THAKUR, RANDHIR
10804578	Not Issued	020	03/19/2004	SHALLOW DOPED JUNCTIONS WITH A VARIABLE PROFILE GRADATION OF DOPANTS	THAKUR, RANDHIR
10789890	Not Issued	020	02/27/2004	SELECTIVE SPACER TECHNOLOGY TO PREVENT METAL OXIDE FORMATION DURING POLYCIDE REOXIDATION	THAKUR, RANDHIR P.S.
10782685	Not Issued	030	02/19/2004	STRUCTURE FOR CONTACT FORMATION USING A SILICON-GERMANIUM ALLOY	THAKUR, RANDHIR P.S.
10781987	Not Issued	030	02/18/2004	METHODS FOR ENHANCING CAPACITORS HAVING ROUGHENED FEATURES TO INCREASE CHARGE-STORAGE CAPACITY	THAKUR, RANDHIR P.S.
10774762	Not Issued	030	02/09/2004	APPROACH TO AVOID BUCKLING IN BPSG BY USING AN INTERMEDIATE BARRIER LAYER	THAKUR, RANDHIR P. S.
10744931	Not Issued	030	12/22/2003	METHODS FOR FORMING WORDLINES, TRANSISTOR GATES, AND CONDUCTIVE INTERCONNECTS, AND WORDLINE, TRANSISTOR GATE, AND CONDUCTIVE INTERCONNECT	THAKUR, RANDHIR P. S.

				STRUCTURES	
10727889	Not Issued	030	12/04/2003	METHOD AND APPARATUS FOR REDUCING FIXED CHARGE IN SEMICONDUCTOR DEVICE LAYERS	THAKUR, RANDHIR P. S
10676498	6784052	150	09/30/2003	METHODS OF FORMING CIRCUITRY	THAKUR, RANDHIR P.S.
10642705	Not Issued	092	08/18/2003	PROCESS FOR GROWING A DIELECTRIC LAYER ON A SILICON-CONTAINING SURFACE USING A MIXTURE OF N2O AND O3	THAKUR, RANDHIR PS
10624817	Not Issued	030	07/22/2003	METHOD FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	THAKUR, RANDHIR
09981549	6717211	150	10/17/2001	SHALLOW DOPED JUNCTIONS WITH A VARIABLE PROFILE GRADATION OF DOPANTS	THAKUR, RANDHIR
09949416	6635568	150	09/07/2001	REFRACTORY METAL ROUGHNESS REDUCTION USING HIGH TEMPERATURE ANNEAL IN HYDRIDES OR ORGANO-SILANE AMBIENTS	THAKUR, RANDHIR P.S.
09932064	6526547	150	08/17/2001	METHOD FOR EFFICIENT MANUFACTURING OF INTEGRATED CIRCUITS	THAKUR, RANDHIR P.S.
09928286	6452678	150	08/10/2001	REFLECTANCE METHOD FOR EVALUATING THE SURFACE CHARACTERISTICS OF OPAQUE MATERIALS	THAKUR, RANDHIR P.S.
09910168	6423649	150	07/20/2001	METHOD AND APPARATUS FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	THAKUR, RANDHIR
09892594	6399459	150	06/27/2001	DOUBLE LAYER ELECTRODE AND BARRIER SYSTEM ON HEMISPHERICAL GRAIN SILICON FOR USE WITH HIGH DIELECTRIC CONSTANT MATERIALS AND METHODS FOR FABRICATING THE SAME	THAKUR, RANDHIR
09879742	6611032	150	06/11/2001	METHODS FOR FORMING WORDLINES, TRANSISTOR GATES, AND CONDUCTIVE	THAKUR, RANDHIR P. S

				INTERCONNECTS, AND WORDLINE, TRANSISTOR GATE, AND CONDUCTIVE INTERCONNECT STRUCTURES	
09875501	Not Issued	093	06/04/2001	METHODS FOR FORMING WORDLINES, TRANSISTOR GATES, AND CONDUCTIVE INTERONNECTS, AND WORDLINE, TRANSISTOR GATE, AND CONDUCTIVE INTERCONNECT STRUCTURES	THAKUR, RANDHIR P.S.
09823133	6404005	150	03/29/2001	METHODS OF FORMING CAPACITORS AND RELATED INTEGRATED CIRCUITRY	THAKUR, RANDHIR P.S.
09793317	6417928	150	02/26/2001	REFLECTANCE METHOD FOR EVALUATING THE SURFACE CHARACTERISTICS OF OPAQUE MATERIALS	THAKUR, RANDHIR P.S.
09793248	6380103	150	02/26/2001	RAPID THERMAL ETCH AND RAPID THERMAL OXIDATION	THAKUR, RANDHIR P.S.
09696058	Not Issued	071	10/25/2000	METHOD FOR FORMING A DIELECTRIC	THAKUR, RANDHIR P.S.
09684069	6627508	150	10/06/2000	METHOD OF FORMING CAPACITORS CONTAINING TANTALUM	THAKUR, RANDHIR P.S.
09676429	6436847	150	09/29/2000	METHOD OF FORMING AN ELECTRONIC DEVICE INCLUDING PREVENTING OXIDATION BY DEPOSITING TWO NITRIDE LAYERS	THAKUR, RANDHIR P.S.
09654093	Not Issued	163	08/31/2000	METHOD TO AVOID THRESHOLD VOLTAGE SHIFT IN THICKER DIELECTRIC FILMS	THAKUR, RANDHIR P.S.
09653086	6521507	150	08/31/2000	SELECTIVE DEPOSITION OF UNDOPED SILICON FILM SEEDED IN CHLORINE AND HYDRIDE GAS FOR A STACKED CAPACITOR	THAKUR, RANDHIR P. S.
09652723	6589877	150	08/31/2000	METHOD OF PROVIDING AN OXIDE	THAKUR, RANDHIR P.
09652426	6217784	150	08/31/2000	HIGH SELECTIVITY ETCHING PROCESS FOR OXIDES	THAKUR, RANDHIR
09651946	6346455	150	08/31/2000	METHOD TO FORM A	THAKUR,

				CORRUGATED STRUCTURE FOR ENHANCED CAPACITANCE	RANDHIR P.S.
09651377	6486020	150	08/29/2000	HIGH PRESSURE REOXIDATION/ANNEAL OF HIGH DIELECTRIC CONSTANT MATERIALS	THAKUR, RANDHIR P.S.
09644759	6514876	150	08/23/2000	PRE-METAL DIELECTRIC RAPID THERMAL PROCESSING FOR SUB-MICRON TECHNOLOGY	THAKUR, RANDHIR P. S.
09630850	6773981	150	08/02/2000	METHODS OF FORMING CAPACITORS	THAKUR, RANDHIR P.S.
09620442	6596595	150	07/20/2000	FORMING A CONDUCTIVE STRUCTURE IN A SEMICONDUCTOR DEVICE	THAKUR, RANDHIR P.S.
09604849	6326321	150	06/27/2000	METHODS OF FORMING A LAYER OF SILICON NITRIDE IN SEMICONDUCTOR FABRICATION PROCESSES	THAKUR, RANDHIR P. S.
09592958	6469388	150	06/13/2000	STRUCTURE FOR CONTACT FORMATION USING A SILICON-GERMANIUM ALLOY	THAKUR, RANDHIR P. S.
09592748	6294461	150	06/13/2000	STRUCTURE FOR CONTACT FORMATION USING A SILICON-GERMANIUM ALLOY	THAKUR, RANDHIR P.S.
09590464	Not Issued	092	06/09/2000	PULSE PRECURSOR DEPOSITION PROCESS FOR FORMING LAYERS IN SEMICONDUCTOR DEVICES	THAKUR, RANDHIR P. S.
09576650	6368887	150	05/22/2000	METHOD OF MONITORING A PROCESS OF MANUFACTURING A SEMICONDUCTOR WAFER INCLUDING HEMISPHERICAL GRAIN POLYSILICON	THAKUR, RANDHIR P.S
09571788	6271152	150	05/16/2000	METHOD FOR FORMING OXIDE LAYER IN FIELD REGIONS FO SEMICONDUCTOR SUBSTRATES IN TWO FORMING STEPS WITH ONE STEP PERFORMED AT AN INCREASED PRESSURE	THAKUR, RANDHIR P.S.
09563909	6316800	150	05/04/2000	BORIDE ELECTRODES AND	THAKUR,

				BARRIERS FOR CELL DIELECTRICS	RANDHIR P.S.
09550189	6157566	150	04/14/2000	REDUCED LEAKAGE DRAM STORAGE UNIT	THAKUR, RANDHIR PS
09544787	Not Issued	163	04/07/2000	FORMING A CONDUCTIVE STRUCTURE IN A SEMICONDUCTOR DEVICE	THAKUR, RANDHIR P.S.
09531988	Not Issued	163	03/20/2000	HIGH SELECTIVITY ETCHING PROCESS FOR OXIDES	THAKUR, RANDHIR
09518154	6602798	150	03/02/2000	METHOD AND APPARATUS FOR REDUCING ISOLATION STRESS IN INTEGRATED CIRCUITS	THAKUR, RANDHIR P S
09517473	6275292	150	03/02/2000	REFLECTANCE METHOD FOR EVALUATING THE SURFACE CHARACTERISTICS OF OPAQUE MATERIALS	THAKUR, RANDHIR P.S.
09514747	6573552	150	02/28/2000	METHOD TO FORM HEMISPHERICAL GRAINED POLYSILICON	THAKUR, RANDHIR P.S.
09506179	6333243	150	02/17/2000	METHOD FOR GROWING FIELD OXIDE TO MINIMIZE BIRDS' BEAK LENGTH	THAKUR, RANDHIR P.S.
09503669	6350648	150	02/14/2000	FORMATION OF CONDUCTIVE RUGGED SILICON	THAKUR, RANDHIR
09503572	6509227	150	02/14/2000	FORMATION OF CONDUCTIVE RUGGED SILICON	THAKUR, RANDHIR

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Application#	Patent#	Status	Date Filed	Title	Inventor Name 51
60351561	Not Issued	159	01/25/2002	ALUMINUM OXIDE CYCLICAL DEPOSITION CHAMBER AND PROCESS	THAKUR, RANDHIR
10881630	Not Issued	020	06/30/2004	CONDUCTOR LAYER NITRIDATION	THAKUR, RANDHIR P.S.
10338523	Not Issued	030	01/07/2003	METHODS TO FORM ELECTRONIC DEVICES AND METHODS TO FORM A MATERIAL OVER A SEMICONDUCTIVE SUBSTRATE	THAKUR, RANDHIR P.S.
10283862	Not Issued	041	10/30/2002	METAL BARRIER INTEGRITY VIA USE OF A NOVEL TWO STEP PVD-ALD DEPOSITION PROCEDURE	THAKUR, RANDHIR P.S.
10278179	Not Issued	161	10/21/2002	METAL NITRIDE FORMATION	THAKUR, RANDHIR P.S.
10277688	Not Issued	094	10/22/2002	STRUCTURE FOR CONTACT FORMATION USING A SILICON-GERMANIUM ALLOY	THAKUR, RANDHIR P.S.
10232206	Not Issued	071	08/29/2002	CAPACITOR HAVING TANTALUM OXYNITRIDE FILM AND METHOD FOR MAKING SAME	THAKUR, RANDHIR P.S.
10232205	Not Issued	041	08/29/2002	CAPACITOR HAVING TANTALUM OXYNITRIDE FILM AND METHOD FOR MAKING SAME	THAKUR, RANDHIR P.S.
10231758	Not Issued	095	08/29/2002	CONDUCTOR LAYER NITRIDATION	THAKUR, RANDHIR P.S.
10228697	6667540	150	08/26/2002	METHOD AND APPARATUS FOR REDUCING FIXED CHARGE IN	THAKUR, RANDHIR P. S.

				SEMICONDUCTOR DEVICE LAYERS	
10223805	Not Issued	041	08/19/2002	CAPACITOR CONSTRUCTIONS WITH A BARRIER LAYER TO THRESHOLD VOLTAGE SHIFT INDUCING MATERIAL	THAKUR, RANDHIR P.S.
10223004	6787482	150	08/14/2002	METHOD TO FORM A DRAM CAPACITOR USING LOW TEMPERATURE REOXIDATION	THAKUR, RANDHIR P. S.
10213812	Not Issued	041	08/07/2002	METHODS FOR FORMING A HIGH DIELECTRIC FILM	THAKUR, RANDHIR P.S.
10212892	6596651	150	08/05/2002	METHOD FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	THAKUR, RANDHIR
10188472	6703690	150	07/02/2002	METHOD AND APPARATUS FOR REDUCING ISOLATION STRESS IN INTEGRATED CIRCUITS	THAKUR, RANDHIR P.S.
10121635	Not Issued	030	04/11/2002	METHOD AND APPARATUS FOR WAFER CLEANING	THAKUR, RANDHIR
10087557	6620740	150	02/28/2002	METHODS TO FORM ELECTRONIC DEVICES	THAKUR, RANDHIR P.S.
10057363	6594013	150	10/29/2001	REFLECTANCE METHOD FOR EVALUATING THE SURFACE CHARACTERISTICS OF OPAQUE MATERIALS	THAKUR, RANDHIR P.S.
10041550	6677247	150	01/07/2002	METHOD OF INCREASING THE ETCH SELECTIVITY OF A CONTACT SIDEWALL TO A PRECLEAN ETCHANT	THAKUR, RANDHIR P.S.
10017557	6645845	150	12/14/2001	INTEGRATED CIRCUITRY AND METHODS OF FORMING CIRCUITRY	THAKUR, RANDHIR P.S.
10010842	6660611	150	12/07/2001	METHOD TO FORM A CORRUGATED STRUCTURE FOR ENHANCED CAPACITANCE WITH PLURALITY OF BORO-PHOSPHO SILICATE GLASS INCLUDING GERMANIUM	THAKUR, RANDHIR P.S.
10008434	Not Issued	030	11/13/2001	NOVEL METHOD, SYSTEM, AND PROCESS FOR ACQUIRING, EVALUATING,	THAKUR, RANDHIR P.S.

				PATENTING, AND MARKETING INNOVATION	
09965240	Not Issued	041	09/26/2001	METHODS FOR ENHANCING CAPACITORS HAVING ROUGHENED FEATURES TO INCREASE CHARGE-STORAGE CAPACITY	THAKUR, RANDHIR P S
09930961	6635547	150	08/17/2001	DRAM CAPACITOR FORMULATION USING A DOUBLE-SIDED ELECTRODE	THAKUR, RANDHIR
09921423	Not Issued	093	08/02/2001	METHOD TO FORM A CORRUGATED STRUCTURE FOR ENHANCED CAPACITANCE	THAKUR, RANDHIR P S
09911580	6414364	150	07/24/2001	ISOLATION STRUCTURE AND PROCESS THEREFOR	THAKUR, RANDHIR
09852449	6383875	150	05/09/2001	METHOD OF FORMING A TRANSISTOR GATE	THAKUR, RANDHIR P S
09846520	6400552	150	04/30/2001	CAPACITOR WITH CONDUCTIVELY DOPED SI-GE ALLOY ELECTRODE	THAKUR, RANDHIR P. S.
09798445	Not Issued	094	03/02/2001	METHOD AND APPARATUS FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	THAKUR, RANDHIR
09797900	6548852	150	03/01/2001	INTEGRATED CIRCUITRY AND METHODS OF FORMING CIRCUITRY	THAKUR, RANDHIR P.S.
09793435	6327040	150	02/26/2001	REFLECTANCE METHOD FOR EVALUATING THE SURFACE CHARACTERISTICS OF OPAQUE MATERIALS	THAKUR, RANDHIR P S
09780166	6355182	150	02/09/2001	HIGH SELECTIVITY ETCHING PROCESS FOR OXIDES	THAKUR, RANDHIR
09774935	6620534	150	01/31/2001	A FILM HAVING ENHANCED REFLOW CHARACTERISTICS AT LOW THERMAL BUDGET	THAKUR, RANDHIR P S
09771441	6337243	150	01/25/2001	SEMICONDUCTOR PROCESSING METHOD OF MAKING A HEMISPHERICAL GRAIN (HSG) POLYSILICON LAYER	THAKUR, RANDHIR P.S.
09761355	Not Issued	093	01/16/2001	HIGH PRESSURE ANNEALS OF INTEGRATED CIRCUIT STRUCTURES	THAKUR, RANDHIR P.S.
09739850	6404669	150	12/18/2000	REDUCED LEAKAGE DRAM	THAKUR,

				STORAGE UNIT	RANDHIR PS
09717941	6448133	150	11/20/2000	METHOD TO FORM A DRAM CAPACITOR USING LOW TEMPERATURE REOXIDATION	THAKUR, RANDHIR P. S.
09713845	6426306	150	11/15/2000	BARRIER LAYER FABRICATION METHODS	THAKUR, RANDHIR P. S.
09712341	6669782	150	11/15/2000	METHOD AND APPARATUS TO CONTROL THE FORMATION OF LAYERS USEFUL IN INTEGRATED CIRCUITS	THAKUR, RANDHIR P.S.
09710546	6593183	150	11/08/2000	SEMICONDUCTOR PROCESSING METHOD USING A BARRIER LAYER	THAKUR, RANDHIR P.S.
09696357	6432841	150	10/25/2000	METHOD FOR FORMING A DIELECTRIC	THAKUR, RANDHIR
09696058	Not Issued	071	10/25/2000	METHOD FOR FORMING A DIELECTRIC	THAKUR, RANDHIR P.S.
09692897	6682970	150	10/19/2000	CAPACITOR/ANTIFUSE STRUCTURE HAVING A BARRIER-LAYER ELECTRODE AND IMPROVED BARRIER LAYER	THAKUR, RANDHIR P.S.
09681828	6541811	150	06/12/2001	CAPACITOR/ANTIFUSE STRUCTURE HAVING A BARRIER-LAYER ELECTRODE AND IMPROVED BARRIER LAYER	THAKUR, RANDHIR P.S.
09655934	6476433	150	09/06/2000	SEMICONDUCTOR MEMORY DEVICE WITH SIMULTANEOUSLY FORMED ELECTRODE AND INTERCONNECTION LAYERS	THAKUR, RANDHIR P.S.
09648839	6403923	150	08/25/2000	SYSTEM FOR CONTROLLING THE TEMPERATURE OF A REFLECTIVE SUBSTRATE DURING RAPID HEATING	THAKUR, RANDHIR P.S.
09642399	6281511	150	08/18/2000	APPARATUS FOR FORMING MATERIALS	THAKUR, RANDHIR P.S.
09604850	6670288	150	06/27/2000	METHODS OF FORMING A LAYER OF SILICON NITRIDE IN A SEMICONDUCTOR FABRICATION PROCESS	THAKUR, RANDHIR P. S.
09539641	6316308	150	03/30/2000	METHODS TO FORM ELECTRONIC DEVICES	THAKUR, RANDHIR P. S.

09506177	6528436	150	02/17/2000	METHOD OF FORMING SILICON NITRIDE LAYER DIRECTLY ON HSG POLYSILICON	THAKUR, RANDHIR P. S.
09483839	6300243	150	01/17/2000	REFRACTORY METAL ROUGHNESS REDUCTION USING HIGH TEMPERATURE ANNEAL IN HYDRIDES OR ORGANO-SILANE AMBIENTS	THAKUR, RANDHIR P. S.

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10454218	Not Issued	041	06/04/2003	FORMING A CONDUCTIVE STRUCTURE IN A SEMICONDUCTOR DEVICE	THAKUR, RANDHIR P.S.
10368069	Not Issued	071	02/18/2003	SELECTIVE DEPOSITION OF UNDOPED SILICON FILM SEEDED IN CHLORINE AND HYDRIDE GAS FOR A STACKED CAPACITOR	THAKUR, RANDHIR P.S.
10366103	Not Issued	030	02/12/2003	METHOD AND APPARATUS FOR WAFER CLEANING	THAKUR, RANDHIR
10352257	Not Issued	030	01/27/2003	APPARATUS FOR CYCLICAL DEPOSITION OF THIN FILMS	THAKUR, RANDHIR P.S.
10325353	Not Issued	041	12/19/2002	METHOD AND APPARATUS TO IMPROVE THICKNESS UNIFORMITY OF SURFACES FOR INTEGRATED DEVICE MANUFACTURING	THAKUR, RANDHIR
10325260	6699752	150	12/19/2002	FORMATION OF CONDUCTIVE RUGGED SILICON	THAKUR, RANDHIR
10319938	Not Issued	041	12/16/2002	DIFFUSION-ENHANCED CRYSTALLIZATION OF AMORPHOUS MATERIALS TO IMPROVE SURFACE ROUGHNESS	THAKUR, RANDHIR
10251440	Not Issued	094	09/20/2002	OPTIMAL SPIKE ANNEAL AMBIENT	THAKUR, RANDHIR
10159892	6673689	150	05/30/2002	DOUBLE LAYER ELECTRODE AND BARRIER SYSTEM ON HEMISPHERICAL GRAIN SILICON FOR USE WITH HIGH DIELECTRIC CONSTANT MATERIALS AND METHODS FOR FABRICATING THE SAME	THAKUR, RANDHIR

10133132	Not Issued	061	04/25/2002	METHOD OF FORMING A SEMICONDUCTOR DEVICE	THAKUR, RANDHIR P.
10121635	Not Issued	030	04/11/2002	METHOD AND APPARATUS FOR WAFER CLEANING	THAKUR, RANDHIR
09415213	6451661	150	10/12/1999	DRAM CAPACITOR FORMULATION USING A DOUBLE-SIDED ELECTRODE	THAKUR , RANDHIR
09386941	6291364	150	08/31/1999	METHOD AND APPARATUS FOR STABILIZING HIGH PRESSURE OXIDATION OF A SEMICONDUCTOR DEVICE	THAKUR , RANDHIR
09386833	6281543	150	08/31/1999	DOUBLE LAYER ELECTRODE AND BARRIER SYSTEM ON HEMISPHERICAL GRAIN SILICON FOR USE WITH HIGH DIELECTRIC CONSTANT MATERIALS AND METHODS FOR FABRICATING THE SAME	THAKUR , RANDHIR
09353574	6479854	150	07/15/1999	CAPACITOR/ANTIFUSE STRUCTURE HAVING A BARRIER-LAYER ELECTRODE AND IMPROVED BARRIER LAYER	THAKUR, RANDHIR P. S.
09258465	6262485	150	02/26/1999	USING IMPLANTS TO LOWER ANNEAL TEMPERATURES	THAKUR , RANDHIR P S
09207394	6159828	150	12/08/1998	SEMICONDUCTOR PROCESSING METHOD OF PROVIDING A DOPED POLYSILICON LAYER	THAKUR , RANDHIR P. S.
09196515	6359310	150	11/20/1998	SHALLOW DOPED JUNCTIONS WITH A VARIABLE PROFILE GRADATION OF DOPANTS	THAKUR , RANDHIR
09192641	6121081	150	11/16/1998	METHOD TO PREPARE HEMI-SPHERICAL GRAIN (HSG) SILICON USING A FLUORINE BASED GAS MIXTURE AND HIGH VACUUM ANNEAL	THAKUR , RANDHIR P. S.
09190840	6204196	150	11/12/1998	METHOD OF FORMING A FILM HAVING ENHANCED REFLOW CHARACTERISTICS AT LOW THERMAL BUDGET	THAKUR , RANDHIR P.
09189920	6194327	150	11/12/1998	RAPID THERMAL ETCH AND RAPID THERMAL OXIDATION	THAKUR , RANDHIR P. S.

09138879	6511892	150	08/24/1998	DIFFUSION-ENHANCED CRYSTALLIZATION OF AMORPHOUS MATERIALS TO IMPROVE SURFACE ROUGHNESS	THAKUR , RANDHIR
09138773	6528364	150	08/24/1998	METHODS TO FORM ELECTRONIC DEVICES AND METHODS TO FORM A MATERIAL OVER A SEMICONDUCTIVE SUBSTRATE	THAKUR , RANDHIR P S
09135474	6265282	150	08/17/1998	A PROCESS FOR MAKING AN ISOLATION STRUCTURE	THAKUR , RANDHIR
09131993	6525384	150	08/11/1998	CONDUCTOR LAYER NITRIDATION	THAKUR , RANDHIR P S
09089445	6737696	150	06/03/1998	DRAM CAPACITOR FORMULATION USING A DOUBLE-SIDED ELECTRODE	THAKUR , RANDHIR
09083257	Not Issued	162	05/21/1998	CAPACITORS, METHODS OF FORMING CAPACITORS, AND INTEGRATED CIRCUITRY	THAKUR , RANDHIR P S
09076333	6150208	150	05/11/1998	DRAM CAPACITORS MADE FROM SILICON-GERMANIUM AND ELECTRODE-LIMITED CONDUCTION DIELECTRIC FILMS	THAKUR , RANDHIR P. S.
09064631	6015743	150	04/22/1998	SEMICONDUCTOR PROCESSING METHOD OF PROVIDING A CONDUCTIVELY DOPED LAYER OF HEMISPHERICAL GRAIN POLYSILICON AND A HEMISPHERICAL GRAIN POLYSILICON LAYER PRODUCED ACCORDING TO THE METHOD	THAKUR , RANDHIR P S
09057153	6316372	150	04/07/1998	METHODS OF FORMING A LAYER OF SILICON NITRIDE IN A SEMICONDUCTOR FABRICATION PROCESS	THAKUR , RANDHIR P S
09017453	6475927	150	02/02/1998	A METHOD OF FORMING A SEMICONDUCTOR DEVICE	THAKUR , RANDHIR P.
09006126	5960294	150	01/13/1998	METHOD OF FABRICATING A SEMICONDUCTOR DEVICE UTILIZING POLYSILICON GRAINS	THAKUR , RANDHIR
08977251	6126847	150	11/24/1997	HIGH SELECTIVITY ETCHING	THAKUR ,

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08937331	6150029	150	09/05/1997	METHOD OF FORMING A FILM HAVING ENHANCED REFLOW CHARACTERISTICS AT LOW THERMAL BUDGET	THAKUR , RANDHIR P. S.
08927603	5926742	150	09/12/1997	CONTROLLING SEMICONDUCTOR STRUCTURAL WARPAGE IN RAPID THERMAL PROCESSING BY SELECTIVE AND DYNAMIC CONTROL OF A HEATING SOURCE	THAKUR , RANDHIR P. S.
08915517	5994240	150	08/13/1997	METHOD FOR CLEANING SEMICONDUCTOR WAFERS AND EQUIPMENT	THAKUR , RANDHIR P S
08914975	6146967	150	08/20/1997	SELECTIVE DEPOSITION OF AMORPHOUS SILICON FILM SEEDED IN A CHLORINE GAS AND A HYDRIDE GAS AMBIENT WHEN FORMING A STACKED CAPACITOR WITH HSG	THAKUR , RANDHIR P S
08904054	6051511	150	07/31/1997	METHOD AND APPARATUS FOR REDUCING ISOLATION STRESS IN INTEGRATED CIRCUITS	THAKUR , RANDHIR P. S.
08902809	Not Issued	041	07/30/1997	SELECTIVE SPACER TO PREVENT METAL OXIDE FORMATION DURING POLYCIDE REOXIDATION	THAKUR , RANDHIR P. S.
08881519	6207587	150	06/24/1997	METHOD FOR FORMING A DIELECTRIC	THAKUR , RANDHIR P S
08842302	5913127	150	04/23/1997	METHOD TO THERMALLY FORM HEMISPHERICAL GRAIN (HSG) SILICON TO ENHANCE CAPACITANCE FOR APPLICATION IN HIGH DENSITY DRAMS	THAKUR , RANDHIR
08808235	6069053	150	02/28/1997	FORMATION OF CONDUCTIVE RUGGED SILICON	THAKUR , RANDHIR
08807443	5937314	150	02/28/1997	DIFFUSION-ENHANCED CRYSTALLIZATION OF AMORPHOUS MATERIALS TO IMPROVE SURFACE ROUGHNESS	THAKUR , RANDHIR
08674782	Not Issued	166	07/03/1996	METHOD FOR CLEANING	THAKUR ,

				SEMICONDUCTOR WAFERS AND EQUIPMENT	RANDHIR P S
08662852	5712186	150	06/12/1996	METHOD FOR GROWING FIELD OXIDE TO MINIMIZE BIRDS' BREAK LENGTH	THAKUR, RANDHIR P. S.
08654573	Not Issued	161	05/29/1996	JUNCTION WITH VARIABLE PROFILE GRADATION OF DOPANT AND METHOD FOR FORMING SAME	THAKUR, RANDHIR
08578825	Not Issued	161	12/26/1995	METHOD TO AVOID THRESHOLD VOLTAGE SHIFT IN THICKER DIELECTRIC FILMS	THAKUR, RANDHIR
08528183	5885869	150	09/14/1995	METHOD FOR UNIFORMLY DOPING HEMISPHERICAL GRAIN POLYCRYSTALLINE SILICON	THAKUR, RANDHIR P S
08496722	5663090	150	06/29/1995	METHOD TO THERMALLY FORM HEMISPHERICAL GRAIN (HSG) SILICON TO ENHANCE CAPACITANCE FOR APPLICATION IN HIGH DENSITY DRAMS	THAKUR, RANDHIR P.
08132599	Not Issued	161	10/06/1993	CONDUCTOR HAVING A POLYCIDE FILM AND A METHOD TO CREATE SAME FOR USE IN ULSI APPLICATIONS	THAKUR, RANDHIR
08106177	Not Issued	161	08/13/1993	DRAM MEMORY USING MICROTRENCH TECHNOLOGY	THAKUR, RANDHIR P. S.

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09447527	6281122	150	11/23/1999	METHOD FOR FORMING MATERIALS	THAKUR , RANDHIR P. S.
09368481	6162666	150	08/04/1999	METHOD TO FORM A DRAM CAPACITOR USING LOW TEMPERATURE REOXIDATION	THAKUR , RANDHIR P. S.
09333770	6730584	150	06/15/1999	METHODS FOR FORMING WORDLINES, TRANSISTOR GATES, AND CONDUCTIVE INTERCONNECTS, AND WORDLINE, TRANSISTOR GATE, AND CONDUCTIVE INTERCONNECT STRUCTURES	THAKUR , RANDHIR P. S.
09310624	6249019	150	05/12/1999	CONTAINER CAPACITOR WITH INCREASED SURFACE AREA AND METHOD FOR MAKING SAME	THAKUR , RANDHIR P. S.
09260994	5969983	150	03/01/1999	CAPACITOR/ANTIFUSE STRUCTURE HAVING A BARRIER-LAYER ELECTRODE AND IMPROVED BARRIER LAYER	THAKUR , RANDHIR P. S.
09229872	6174651	150	01/14/1999	METHOD FOR DEPOSITING ATOMIZED MATERIALS ONTO A SUBSTRATE UTILIZING LIGHT EXPOSURE FOR HEATING	THAKUR , RANDHIR P. S.
09229518	6282080	150	01/13/1999	SEMICONDUCTOR CIRCUIT COMPONENTS AND CAPACITORS	THAKUR , RANDHIR P. S.
09207394	6159828	150	12/08/1998	SEMICONDUCTOR PROCESSING METHOD OF PROVIDING A DOPED	THAKUR , RANDHIR P. S.

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09137780	6255186	150	08/20/1998	METHODS OF FORMING INTEGRATED CIRCUITRY AND CAPACITORS HAVING A CAPACITOR ELECTRODE HAVING A BASE AND A PAIR OF WALLS PROJECTING UPWARDLY THEREFROM	THAKUR , RANDHIR P. S.
09071860	6172387	150	05/04/1998	SEMICONDUCTOR INTERCONNECTION STRUCTURE AND METHOD	THAKUR , RANDHIR P. S.
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09042791	6111285	150	03/17/1998	BORIDE ELECTRODES AND BARRIERS FOR CELL DIELECTRICS	THAKUR , RANDHIR P. S.
09033064	6162744	150	02/28/1998	METHOD OF FORMING HIGH-K OXYGEN-CONTAINING DIELECTRIC LAYERS INCLUDING MANUFACTURE OF CAPACITORS AND DRAM CELLS	THAKUR , RANDHIR P. S.
09031991	6075291	150	02/27/1998	STRUCTURE FOR CONTACT FORMATION USING A SILICON-GERMANIM ALLOY	THAKUR , RANDHIR P. S.
09031407	6291868	150	02/26/1998	FORMING A CONDUCTIVE STRUCTURE IN A SEMICONDUCTOR DEVICE	THAKUR , RANDHIR P. S.
09028979	6592661	150	02/25/1998	METHOD FOR PROCESSING WAFERS IN A SEMICONDUCTOR FABRICATION SYSTEM	THAKUR , RANDHIR P. S.
09024876	6110777	150	02/17/1998	METHOD OF MONITORING A PROCESS OF MANUFACTURING A SEMICONDUCTOR WAFER INCLUDING SPACE HEMISPHERICAL GRAIN POLYSILICON	THAKUR , RANDHIR P. S.
08972370	Not Issued	161	11/18/1997	HIGH PERFORMANCE	THAKUR ,

				PMOSFET USING SPLIT-POLYSILICON COMOS PROCESS INCORPORATING ADVANCED STACKED CAPACITOR CELLS FOR FABRICATING MULTI-MEGABIT DRAMS	RANDHIR P. S.
08968382	5966595	150	11/12/1997	METHOD TO FORM A DRAM CAPACITOR USING LOW TEMPERATURE REOXIDATION	THAKUR , RANDHIR P. S.
08844169	6072226	150	04/18/1997	FIELD ISOLATION STRUCTURE FORMED USING OZONE OXIDATION AND TAPERING	THAKUR , RANDHIR P. S.
08820712	5989973	150	03/18/1997	SEMICONDUCTOR PROCESSING METHOD OF PROVIDING A CONDUCTIVELY DOPED LAYER OF HEMISPHERICAL GRAIN POLYSILICON AND A HEMISPHERICAL GRAIN POLYSILICON LAYER PRODUCED ACCORDING TO THE METHOD	THAKUR , RANDHIR P. S.
08803174	6015997	150	02/19/1997	SEMICONDUCTOR STRUCTURE HAVING A DOPED CONDUCTIVE LAYER	THAKUR , RANDHIR P. S.
08795170	5863327	150	02/10/1997	APPARATUS FOR FORMING MATERIALS	THAKUR , RANDHIR P. S.
08779602	5946588	150	01/07/1997	LOW TEMPERATURE SUB-ATMOSPHERIC OZONE OXIDATION PROCESS FOR MAKING THIN GATE OXIDES	THAKUR , RANDHIR P. S.
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				DESIRABLE IMPURITIES INTO HIGH PRESSURE OXIDES	
08676587	5885896	150	07/08/1996	USING IMPLANTS TO LOWER ANNEAL TEMPERATURES	THAKUR , RANDHIR P. S.
08594652	Not Issued	166	02/02/1996	METHOD AND APPARATUS FOR REDUCING FIXED CHARGE IN SEMICONDUCTOR DEVICE LAYERS	THAKUR , RANDHIR P. S.
08593499	5891744	150	01/29/1996	METHOD OF MONITORING A PROCESS OF MANUFACTURING A SEMICONDUCTOR WAFER INCLUDING HEMISPHERICAL GRAIN POLYSILICON	THAKUR , RANDHIR P. S.
08582728	5851929	150	01/04/1996	CONTROLLING SEMICONDUCTOR STRUCTURAL WARPAGE IN RAPID THERMAL PROCESSING BY SELECTIVE AND DYNAMIC CONTROL OF A HEATING SOURCE	THAKUR , RANDHIR P. S.
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08539809	Not Issued	166	10/05/1995	METHOD TO FORM A DRAM CAPACITOR USING LOW TEMPERATURE REOXIDATION	THAKUR , RANDHIR P. S.
08538732	5672539	150	10/03/1995	METHOD FOR FORMING AN IMPROVED FIELD ISOLATION STRUCTURE USING OZONE ENHANCED OXIDATION AND TAPERING	THAKUR , RANDHIR P. S.
08518525	Not Issued	166	08/23/1995	SEMICONDUCTOR PROCESSING METHOD OF FORMING HEMISPHERICAL GRAIN POLYSILICON AND A SUBSTRATE HAVING A HEMISPHERICAL GRAIN POLYSILICON LAYER	THAKUR , RANDHIR P. S.

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08312744	5913149	150	09/14/1994	METHOD FOR FABRICATING STACKED LAYER SILICON NITRIDE FOR LOW LEAKAGE AND HIGH CAPACITANCE	THAKUR , RANDHIR P. S.
08245422	5561612	150	05/18/1994	CONTROL AND 3-DIMENSIONAL SIMULATION MODEL OF TEMPERATURE VARIATIONS IN A RAPID THERMAL PROCESSING MACHINE	THAKUR , RANDHIR P. S.
08166058	5407534	150	12/10/1993	METHOD TO PREPARE HEMI-SPHERICAL GRAIN (HSG) SILICON USING A FLUORINE BASED GAS MIXTURE AND HIGH VACUUM ANNEAL	THAKUR , RANDHIR P. S.
08149856	Not Issued	161	11/10/1993	THERMAL PROCESS FOR FORMING HIGH VALUE RESISTORS	THAKUR , RANDHIR P. S.
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